

In the Claims

The following listing of the claims replaces all previous listings.

1.-20. (Canceled)

21. (Original) A method for removing a hackle of an optical fiber from an end face of a ferrule, the method comprising:

placing the ferrule in a fixture; and
mechanically bringing the end face of the ferrule into contact with a polishing structure such that the hackle is removed.

22. (Original) The method of claim 21, wherein the end face of the ferrule is brought into contact with the polishing structure by lowering the fixture toward the polishing structure with a lift mechanism.

23. (New) The method of claim 21, further comprising sensing a polishing pressure applied by the polishing structure to the ferrule.

24. (New) The method of claim 21, wherein the step of mechanically bringing the end face of the ferrule into contact with the polishing structure further comprises moving the polishing structure in a polishing sequence.

25. (New) The method of claim 24, wherein the polishing structure is rotated in an orbital motion about a central axis.

26. (New) The method of claim 24, further comprising monitoring an elapsed time of the polishing sequence.

27. (New) The method of claim 21, further comprising:
moving the end face of the ferrule away from the polishing structure;
removing the fixture; and

using the fixture in a subsequent polishing process.

28. (New) A method for removing a hackle of an optical fiber, the method comprising:
clamping a plurality of ferrules into a fixture;
coupling the fixture to an arm of a polishing apparatus including a polishing surface;
moving the arm of the polishing apparatus using a mechanical lift so that the plurality of ferrules come into contact with the polishing surface; and
driving the polishing surface using a drive mechanism such that the hackle is removed.
29. (New) The method of claim 28, further comprising sensing a polishing pressure applied between the plurality of ferrules and the polishing surface.
30. (New) The method of claim 28, wherein the step of driving the polishing surface further comprises moving the polishing surface in a polishing sequence.
31. (New) The method of claim 30, wherein the polishing surface is rotated in an orbital motion about a central axis.
32. (New) The method of claim 30, further comprising monitoring an elapsed time of the polishing sequence.
33. (New) The method of claim 28, further comprising:
moving the arm of the polishing apparatus using the mechanical lift to move the plurality of ferrules away from the polishing surface;
removing the fixture from the polishing apparatus; and
using the fixture in a subsequent polishing process.